

MAR05-2004-004415

Abstract for an Invited Paper
for the MAR05 Meeting of
the American Physical Society

Tunneling magnetoresistance oscillation effect in double-barrier magnetic tunnel junctions

XIU-FENG HAN, Institute of Physics, CAS

In this work, we present the fabrication of the double barrier magnetic tunnel junction (DBMTJ) of Ta (5 nm)/Cu (30 nm)/Ni₇₉Fe₂₁ (10 nm)/Ir₂₂Mn₇₈ (12 nm)/Co₇₅Fe₂₅ (4 nm)/Ru (0.9 nm)/Co₇₅Fe₂₅ (4 nm) /Al (1 nm)-oxide/Co₇₅Fe₂₅ (1 nm)/Ni₇₉Fe₂₁ (2 nm)/ Co₇₅Fe₂₅ (1 nm)/Al (1 nm)- oxide/ Co₇₅Fe₂₅ (4 nm)/Ru (0.9 nm)/Co₇₅Fe₂₅ (4 nm) / Ir₂₂Mn₇₈ (12 nm)/Ni₇₉Fe₂₁ (10 nm)/Cu (30 nm)/Ta (5 nm) on Si/SiO₂ wafer using Magnetron Sputtering System. Lithographic technique combined with Ar ion-beam etching was adopted in the micro-fabrication processes. Active area of a patterned elliptic DBMTJ element was $3 \times 6 \pi \mu\text{m}^2$. Thus, TMR ratio of 27% and 42.2%, and resistance-area product RS of around 13.6 and 17.5 $\text{k}\Omega\mu\text{m}^2$ at 300 K and 4.2 K were obtained respectively. A tunneling magnetoresistance oscillation phenomenon with respect to the bias voltage was first observed in this experiment. Such an effect can be attributed to either the spin-polarized electron coherent and resonant tunneling or the quantum well states. It may open up the possibility of developing novel spintronic devices such as resonant-tunneling spin transistors, etc.